

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	: Masaharu Nagai et al.	Art Unit	: 1795
Serial No.	: 10/694,986	Examiner	: Daborah Chacko Davis
Filed	: October 29, 2003	Conf. No.	: 5334
Title	: METHOD FOR REMOVING RESIST PATTERN AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE		

**MAIL STOP AF**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT IN REPLY TO ACTION OF OCTOBER 8, 2009

Please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.